

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Shen et al.	Group Art Unit: 1746
Serial No: 09/507,629	Examiner: Allan W. Olsen
Filed: February 18, 2000	Attorney Docket No: 001945 USA P03/SILICON/JB
Title: SELF-CLEANING PROCESS FOR ETCHING SILICON-CONTAINING MATERIAL	July 23, 2002 San Francisco, California

AMENDMENT

Box Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Examiner Olsen:

This communication is filed in response to the Office Action mailed on March 29, 2002, and is being filed within four months thereof with a request for one month extension of time.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:	
Box Fee Amendment Commissioner for Patents Washington, D.C. 20231	
By <u>Kathleen Bliven</u> Kathleen Bliven	Dated <u>7-24-02</u>

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